

U.S. Department of Commerce, Patent and Trademark Office		Docket No.	Serial No.
(PTO Form 1449 modified)		YOR920030386US1	10/674,719
INFORMATION DISCLOSURE STATEMENT BY APPLICANT		Applicant Clevenger, et al.	Confirmation No.: 3989
(Use several sheets if necessary)		Filing Date	Group
Examiner		September 30, 2003	1753

U.S. Patent Documents

*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
TTN	A1	4,709,225	11/24/1987	Welland et al.	340	347	
TTN	A2	6,426,903	07/30/2002	Clevenger et al.	365	200	
	A3						
	A4						
	A5						
	A6						

Foreign Patent Documents

*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
	B1						<input type="checkbox"/>	<input type="checkbox"/>
	B2						<input type="checkbox"/>	<input type="checkbox"/>
	B3						<input type="checkbox"/>	<input type="checkbox"/>

OTHER ART

*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.
TTN	C1	Dutt, et al., "Integrated Circuit SNR improvement using Dielectric Altering Compound, Laser Trim and FIB system," Proc. 26th International Symposium for Testing and Failure Analysis (ISTFA2000), (ASM International, Materials Park, Ohio) pp. 323-326 (2000).
TTN	C2	Kotecki, et al., "(Ba,Sr)TiO ₃ dielectrics for future stacked-capacitor DRAM," J. Res. Develop, 43 (3), May 1999
TTN	C3	LASERtrim® Tuning Application Notes, "Active Trimming Characteristics of Lasertrim® Chip Capacitors," Johanson Technology, Inc. © 1998 Datasheet LZT983
TTN	C4	Liu, et al., "Effective Strategy for Porous Organosilicate to Suppress Oxygen Ashing Damage," Electrochemical and Solid State Letters, 5(3), G11-G14, 2002
TTN	C5	Machalett, et al., "Focused-ion-beam writing of electrical connections into platinum oxide films," Applied Physics Letters, 76 (23), June 5, 2000
TTN	C6	Wang, et al., "Structural and Electrical Characteristics of Low-Dielectric Constant Porous Hydrogen Silsesquioxane for Cu Metallization," J. The Electrochemical Soc., 150 (8), F141-F146, 2003

Examiner [Signature] Date Considered 8/24/2004

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.